

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masahiko NAKAMORI et al.
App. No : 10/536,621
Filed : May 26, 2005
For : POLISHING PAD AND METHOD OF
PRODUCING SEMICONDUCTOR
DEVICE
Examiner : Sylvia Macarthur
Art Unit : 1792
Conf No. : 9275

AMENDMENT

Mail Stop Amendment

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action, dated October 6, 2009, Applicant respectfully submits the following amendments and remarks in connection with the above-captioned application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.